

Serial No. 09/882,141



IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

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Applicant(s): Wang, Y.

Case: AM1562D1

Conf No.: 8856

Serial No.: 09/882,141

Filed: June 15, 2001

Examiner: Umez Eronini, L.

Group Art Unit: 1765

Title: METHOD OF ETCHING HIGH ASPECT RATIO OPENINGS IN SILICON

ASSOCIATE POWER OF ATTORNEY

COMMISSIONER FOR PATENTS
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S I R:

Applicants' attorney, Donald Verplancken, hereby appoints:

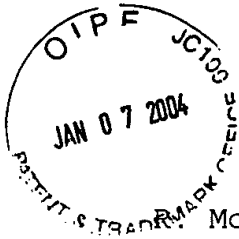
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as Associate Attorneys with full powers to prosecute this application, to make alterations and amendments therein, to inspect and make copies thereof and of any papers in any appellate and inter-party proceedings in which it may be involved, and to transact all business in the United States Patent and Trademark Office connected therewith.

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Respectfully submitted,

12/24/03

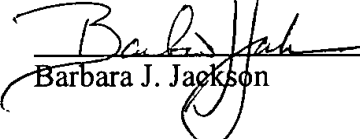

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CERTIFICATE OF MAILING

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Date: 1-5-2004


Barbara J. Jackson